



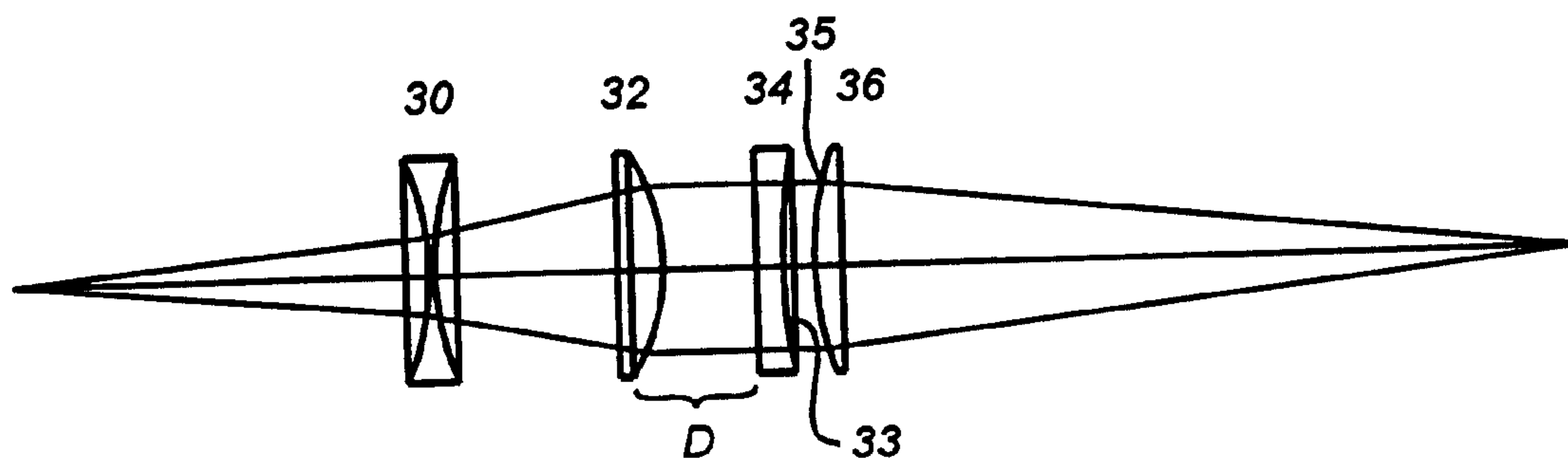
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(54) **DISPOSITIF ET TECHNIQUE AFFERENTE DE PRODUCTION  
DE FAISCEAU LASER AMELIORE**

(54) **APPARATUS AND METHOD FOR PRODUCING AN IMPROVED  
LASER BEAM**



(57) Cette invention a trait à un faisceau laser amélioré des plus utile en matière de traitement de surface d'un matériau ainsi qu'au dispositif de production de ce faisceau laser amélioré. Ce faisceau est doté d'une distribution d'énergie plus intense au niveau des régions extérieures qu'à celui de la région centrale. L'invention porte sur un dispositif comprenant un élément sphérique d'énergie et des éléments optiques cylindriques alignés de manière à focaliser et/ou mettre en forme un faisceau laser pour lui donner un nouveau profil, des plus utile pour un traitement de surface de matériaux. Elle concerne, de surcroît, une technique d'utilisation de ce dispositif pour focaliser et/ou mettre en forme un faisceau laser afin d'obtenir des améliorations de surface par laser, dénommées dans le descriptif "LISI".

(57) This invention relates to an improved laser beam useful in material surface processing and an apparatus for producing the improved laser beam. The improved laser beam of the present invention comprises a power distribution that is more intense at the outer regions than in the central region. The invention includes an apparatus comprising a power spherical and cylindrical optical elements aligned to focus and/or shape a laser beam into a novel profile useful in material surface processing. The invention further includes a method of using this apparatus to focus and/or shape a laser beam for producing Laser Induced Surface Improvements, hereinafter referred to as "LISI".



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<b>(21) International Application Number:</b> PCT/US99/15421 <b>(22) International Filing Date:</b> 9 July 1999 (09.07.99) <b>(30) Priority Data:</b> 09/127,396                      31 July 1998 (31.07.98)                      US <b>(71) Applicant:</b> THE UNIVERSITY OF TENNESSEE RE- SEARCH CORPORATION [US/US]; Suite 403, 1534 White Avenue, Knoxville, TN 37996-1527 (US). <b>(72) Inventors:</b> HOPKINS, John, A.; 108 Quail Drive, Tullahoma, TN 37388 (US). SCHWARTZ, Frederick, A.; 469 Carole Ann Drive, Woodbury, TN 37190 (US). MCCAY, Mary, Helen; P.O. Box 9, Monteagle, TN 37356 (US). MCCAY, Thurman, Dwayne; P.O. Box 9, Monteagle, TN 37356 (US). DAHOTRE, Narendra, B.; 102 Blanton Court, Tullahoma, TN 37388 (US). BIBLE, John, Brice; 1075 Swedens Cove Road, South Pittsburg, TN 37380 (US). <b>(74) Agent:</b> REDANO, Richard, T.; Rosenblatt & Redano, P.C., Suite 500, One Greenway Plaza, Houston, TX 77046 (US).	<b>(81) Designated States:</b> AU, BR, CA, CN, CZ, IL, IN, JP, KR, RU, European patent (AT, BE, CH, CY, DE, DK, ES, FI, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE).  <b>Published</b> <i>With international search report.</i> <i>With amended claims.</i>	
<b>(54) Title:</b> APPARATUS AND METHOD FOR PRODUCING AN IMPROVED LASER BEAM		
<b>(57) Abstract</b> <p>This invention relates to an improved laser beam useful in material surface processing and an apparatus for producing the improved laser beam. The improved laser beam of the present invention comprises a power distribution that is more intense at the outer regions than in the central region. The invention includes an apparatus comprising a power spherical and cylindrical optical elements aligned to focus and/or shape a laser beam into a novel profile useful in material surface processing. The invention further includes a method of using this apparatus to focus and/or shape a laser beam for producing Laser Induced Surface Improvements, hereinafter referred to as "LISI".</p>		

**Title:           APPARATUS AND METHOD FOR PRODUCING  
                  AN IMPROVED LASER BEAM**

## **BACKGROUND OF THE INVENTION**

### **1.    Field of the Invention**

This invention relates to an improved laser beam useful in material surface processing and an apparatus for producing the improved laser beam.

5    The improved laser beam of the present invention comprises a power distribution that is more intense at the outer regions than in the central region.

The invention includes an apparatus comprising optical elements aligned to focus and/or shape a laser beam into a novel profile useful in material surface processing. The laser beam and apparatus of the present invention are useful  
10 for producing Laser Induced Surface Improvements, hereinafter referred to as "LISI".

### **2.    Description of the Prior Art**

Laser beams have been used to treat and/or process a workpiece, such as a piece of metal. Prior art devices employing laser beams for materials  
15 processing have comprised a beam delivery system and a movement system for moving the workpiece relative to the beam. The process effect that the beam has upon the workpiece is a function of many variables, including but

not limited to, power distribution and beam shape. Uniform processing of the workpiece surface by the beam is normally desired.

One family of prior art beam processing devices have the disadvantage of nonuniform surface processing because the beams used by such devices have Gaussian or normal power distributions. Jones et al., "Laser-beam Analysis Pinpoints Critical Parameters", Laser Focus World (January 1993). Another type of prior art laser beam has an equalized or uniform power distribution across the cross sectional area of the beam. Such a beam is described in U.S. Patent No. 5,124,993. Such an equalized power distribution can result in less energy deposition at the outer regions of the laser beam irradiation zone due to increased heat transfer in these regions.

This processing nonuniformity results in surface irregularities in the processed workpiece and nonuniform processing depth under the surface area of the workpiece irradiated by the beam. Prior art beam configurations are typically circular. The power density of such circular beams is greatest at the center, thereby resulting in a maximum energy deposition at the center of the beam. The power distribution of typical prior art beams is shown in Figure 1A.

In LSI processes, where the power at point A is constant as a function of time, the energy deposition at point A,  $ED_A$ , is proportional to the product

of the power at point A,  $P_A$ , and the length of time, T, that point A was irradiated as shown. Where the power distribution is spatially nonuniform, the resulting energy deposition distribution is proportionally nonuniform.

5 Another drawback of the Gaussian power distribution of prior art beams is that the power density and corresponding energy deposition decline as a function of radial distance from the beam center. Accordingly, workpieces processed with such prior art beams are overprocessed in the central beam region and underprocessed in the outer beam regions. The depth of processing is proportional to the power distribution. The processed region is referred to herein as "the melt region". A typical melt region of a prior art beam having a Gaussian distribution is shown in Figure 1B. The temperature history resulting from the melt region profile depicted in Figure 1B and the power distribution in Figure 1A, is shown in Figure 1C.

15 Prior art processing methods employ beam overlap during processing of the workpiece to increase the processing depth of the underprocessed outer regions. For LSI processes, surface characteristics such as smoothness and homogeneity of composition are important, particularly for hardness and corrosion resistant properties. The beam overlap required with prior art beam processing methods results in nonuniformities in processing

depth, composition and surface profile. All of these nonuniformities are undesirable.

In LSI processes employing the deposition of a precursor material on the workpiece prior to irradiation, the low power densities in the outer region of the circular beam can result in the melting and removal of the precursor material before it is incorporated into the substrate melt. This can result in nonprocessed irradiated regions.

The efficiency of beam processing systems is a function of many variables, including but not limited to beam shape, size and power distribution. Prior art beam processing devices have the disadvantage of inefficient processing rates, resulting in part from, small beam area, nonuniform power distribution and circular beam shape.

The present invention offers the advantages of (a) improved power distribution, (b) improved surface quality, and (c) improved surface processing rate. These advantages are achieved through the use of a beam shaping and focusing apparatus that produces an improved laser beam with a novel power distribution that is increased at the outer regions relative to the central region. Improved surface quality results from the improved power distribution of the present invention. The improved processing rate results from the larger, noncircular beam surface area, and the more uniform power distribution.

## **SUMMARY OF THE INVENTION**

The present invention comprises an improved laser beam for material surface processing as well as an apparatus for producing this improved laser beam.

5           The laser beam further comprises a power distribution that is substantially constant in the central region, increased at the outer regions, and which decreases in a substantially step function fashion at the end regions. The term "substantially constant in the central region", as used herein, means that the maximum range of power distribution variance in the central region  
10 is less than 7.5% of the maximum power level in the central region.

This power distribution resembles the head of a bat and is hereinafter referred to as a "bat ears" distribution. The ratio of the peak intensity or magnitude of the power in the outer regions to the average intensity or magnitude of power in the central region is greater than or equal to 1.2.

15           The substantially constant distribution in the central region provides substantially uniform energy deposition and material processing in the central region. The increased power distribution at the outer regions compensates for the increased energy or heat flux in this region.

20           The present invention may be used for LSI processing of workpieces having sufficient volume such that the region of the workpiece outside the

energy deposition region (the nonenergy deposition region) acts as a large heat sink. The heat sink properties of the workpiece causes the increased energy or heat flux at the interface between the energy deposition region and the nonenergy deposition region.

5           The substantially step function decrease in power distribution at the end regions provides for controlled material processing in a region approximately equal to the width of the power distribution. This provides improved material processing where the laser beam is applied to the workpiece along contiguous parallel paths. In such processing, it is desirable to minimize beam overlap  
10 because such overlap increases the energy deposition in overlapping regions relative to the energy deposition in the central region of the beam, and decreases area coverage processing rates.

          An apparatus of the present invention is also directed toward a combination of optical elements for producing the laser beam of the present  
15 invention. This combination of optical elements comprises a collimating optical element, a first cylindrical optical element, and a second cylindrical optical element.

          The apparatus is comprised of optical elements oriented to obtain described characteristics of dimension and energy distribution. The apparatus  
20 provides for appropriate focusing of collimated or uncollimated input laser

beams and may be configured to occupy minimal volume. The focal length of the apparatus may be modified to meet existing or desired performance requirements.

Because operation will typically occur at conditions other than those for a corresponding circular beam, the amount of back-reflected energy and subsequent likelihood of damage may be minimized for applications with a fiber optically delivered input laser beam. The apparatus may be designed with active or passive cooling of optical elements to allow continuous operation at high power throughput conditions.

A gas delivery system may be incorporated with the apparatus to assist the laser processing, cool the apparatus, or provide a means of preventing contamination of the optical elements. The apparatus may be made of any structural material, but would likely include opaque walls for beam safety considerations. The inner and outer wall surfaces may be coated to increase absorption of any spurious reflections. A protective cover glass could also be used to protect optics from contamination without altering the effectiveness of the apparatus. The apparatus could be designed so that it would breakaway from a mounting bracket rather than break itself.

### DESCRIPTION OF DRAWINGS

Figure 1A depicts a Gaussian power distribution of a prior art beam.

Figure 1B depicts a typical melt region of the prior art beam depicted in Figure 1A.

Figure 1C depicts a temperature history of a prior art beam resulting from the melt region profile depicted in Figure 1B and the power distribution depicted in Figure 1A.

Figure 2A depicts the power distribution in the width dimension of the laser beam of the present invention.

Figure 2B depicts the power distribution in the length dimension of the laser beam of the present invention.

Figure 2C depicts a top view of the rectangular cross sectional profile of a laser beam of the present invention.

Figure 3 depicts a side view of the apparatus embodiment of the present invention.

Figure 4 depicts a top view of the apparatus embodiment of the present invention.

Figure 5 depicts an isometric view of the apparatus embodiment of the present invention.

### DESCRIPTION OF THE PREFERRED EMBODIMENTS

In a preferred embodiment, the laser beam of the present invention has a rectangular cross sectional profile **20** comprising a width dimension **22** and a length dimension **24**, as shown in Figure 2C. In a preferred embodiment, the width dimension of said beam is at least 8 times the size of the length

dimension of said beam. The ratio of the width dimension to the length dimension measured at location of half maximum intensity is hereinafter referred to as "aspect ratio".

As shown in Figure 2A, the laser beam of the present invention  
5 comprises a power distribution in the width dimension that is substantially constant in the central region 10, increased at the outer regions 12, and which decreases in a substantially step function fashion at the end regions 14 of the width dimension. The ratio of the intensity or magnitude of the power distribution in the outer regions to the intensity or magnitude in the central  
10 region is greater than or equal to 1.2. This ratio is hereinafter referred to as the "outer to central intensity ratio".

In a preferred embodiment, as shown in Figure 2A, the central region extends at least 50% of the width of the beam. In another preferred embodiment, as shown in Figure 2A, the central region extends in a range of  
15 60%–75% of the width of the beam.

In a preferred embodiment, the power distribution in the length dimension is substantially constant as shown in Figure 2B. In a preferred embodiment, as shown in Figure 2B, the size of the length dimension is less than one millimeter.

In a preferred embodiment, the laser beam of the present invention is selectively moveable along an axis parallel to the length dimension of said beam.

An apparatus of the present invention is also directed to shaping a laser beam emitted from a laser source to have a peak outer to average central intensity ratio greater than or equal to 1.2. This apparatus is depicted in Figures 3 and 4. It comprises a collimating optical element 32 positioned to collimate a laser beam emitted from a source. The invention further comprises a first cylindrical optical element 34 having a first curved outer surface 33. The first cylindrical optical element is positioned to receive a collimated laser beam from the collimating optical element. The first cylindrical optical element is spaced 0.1 mm to 5,000.0 millimeters from the collimating optical element. This variable spacing distance is denoted by the letter "D" in Figure 3.

The invention further comprises a second cylindrical optical element 36 having a second curved outer surface 35 that is oriented in a range of 89.5 degrees to 90.5 degrees out of rotational alignment with the first curved surface. The second cylindrical optical element is positioned to receive a laser beam from the first cylindrical optical element. In a preferred embodiment, the first and second curved surfaces face each other.

As shown in Figures 3 and 4, a preferred embodiment of this invention further comprises a biconcave lens 30 positioned between a laser beam

source and the collimating optical element, so as to project a more divergent laser beam on said collimating optical element than would exist without the biconcave lens.

5 In another preferred embodiment, the invention further comprises a laser source 71 capable of emitting laser light having a wave length of 1.06 microns and further comprising a 600 micron diameter fiber 72 from which said laser beam exits as shown in Figure 5. In a preferred embodiment, the laser beam has a divergence angle of 4.4 degrees. In this preferred embodiment, the lens may be constructed of fused silica glass and would further comprise an  
10 antireflection coating suitable for use with normal incidence radiation having a wave length of 1.06 microns.

In another preferred embodiment, the biconcave lens has a focal length of 75 mm and is positioned 98 mm from the effective point source location of the laser beam. The collimating optical element is a spherical optical element  
15 having a focal length of 100 mm and located 41.3 mm from the biconcave lens.

In a preferred embodiment, the first cylindrical optical element is a cylindrical lens having a focal length of 200 mm, located 22 mm from the collimating optical element. In a preferred embodiment, the second cylindrical optical element is a cylindrical lens having a focal length of 152.4 mm and  
20 located 5 mm from the first cylindrical optical element. The second cylindrical

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optical element is rotated 90 degrees around the axis of beam travel with respect to the first cylindrical optical element and is oriented to have its curved surface facing the first cylindrical optical element as shown in Figure 5. In a preferred embodiment, the focal plane 73 at which the desired energy distribution is obtained is located 167.2 mm from the second cylindrical optical element.

The foregoing disclosure and description of the invention are illustrative and explanatory. Various changes in the size, shape, and materials, as well as in the details of the illustrative construction may be made without departing from the spirit of the invention.

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IPER/US 14 FEB 2000**WHAT IS CLAIMED IS:**

- 1        1.     A laser beam comprising a central region and two outer regions,  
2            each of said outer regions comprising an outer edge, said laser  
3            beam comprising a power distribution that is substantially constant  
4            in the central region, increased at the outer regions, and which  
5            decreases at the outer edges such that the peak outer to average  
6            central intensity ratio of said beam is greater than or equal to 1.2.
  
- 1        2.     The laser beam of claim 1 wherein said laser beam has a  
2            rectangular cross sectional profile comprising a width dimension and  
3            a length dimension.
  
- 4        3.     The laser beam of claim 2 wherein said central region extends at  
5            least 50% of the width of said beam.
  
- 1        4.     The laser beam of claim 3 wherein said central region extends  
2            60-75% of the width of said beam.

1 5. The laser beam of claim 2 wherein said beam has an aspect ratio  
2 greater than or equal to 8.

1 6. Deleted

2 7. The laser beam of claim 2 wherein the size of said length dimension  
3 is less than one millimeter.

1 8. Deleted

1 9. A laser beam having a rectangular cross sectional profile comprising  
2 a width dimension and a length dimension, said width being at least  
3 eight times the size of said length dimension, said beam further  
4 comprising a power distribution in the width dimension, said power  
5 distribution comprising a central region and outer regions comprising  
6 outer edges, said distribution being substantially constant in the  
7 central region, increased at the outer regions, and decreasing at the  
8 outer edges of said width dimension.

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1 10. The laser beam of claim 9 wherein said central region extends at  
2 least 50% of the width of said beam.

1 11. The laser beam of claim 9 wherein the peak outer to average central  
2 intensity ration of said beam in the width dimension is greater than  
3 or equal to 1.2.

1 12. Deleted

1 13. An apparatus for shaping a laser beam emitted from a laser beam  
2 source to have a peak outer to average central intensity ratio greater  
3 than or equal to 1.2 comprising:  
4 a. a collimating optical element positioned to collimate a laser  
5 beam emitted from a fiber optic source;  
6 b. a first cylindrical optical element having a first curved outer  
7 surface, said first cylindrical optical element being positioned  
8 to receive a collimated laser beam from said collimating  
9 optical element, wherein said first cylindrical optical element  
10 is spaced 0.1 to 5,000.0 millimeters from said collimating  
11 optical element;

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- 12 c. a second cylindrical optical element having a second curved  
13 outer surface that is oriented 89.5 - 90.5 degrees out of  
14 rotational alignment with said first curved surface, said second  
15 cylindrical optical element being located 5 millimeters from  
16 said first cylindrical optical element; and
- 17 d. a bioconcave lens positioned between a laser beam source  
18 and said collimating optical element so as to project a more  
19 divergent laser beam on said collimating optical element.

1 14. The apparatus of claim 13 wherein said collimating optical element  
2 is a collimating lens.

1 15. The apparatus of claim 13 wherein said first and second cylindrical  
2 optical elements are cylindrical lenses.

1 16. Deleted

1 17. The apparatus of claim 13 wherein the focal length of said first  
2 cylindrical optical element is 200 millimeters.

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1 18. The apparatus of claim 13 wherein the focal length of said second  
2 cylindrical optical element is 152.4 millimeters.

1 19. The apparatus of claim 13 wherein said first and second curved  
2 surfaces face each other.

1 20. Deleted

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FIG. 1A

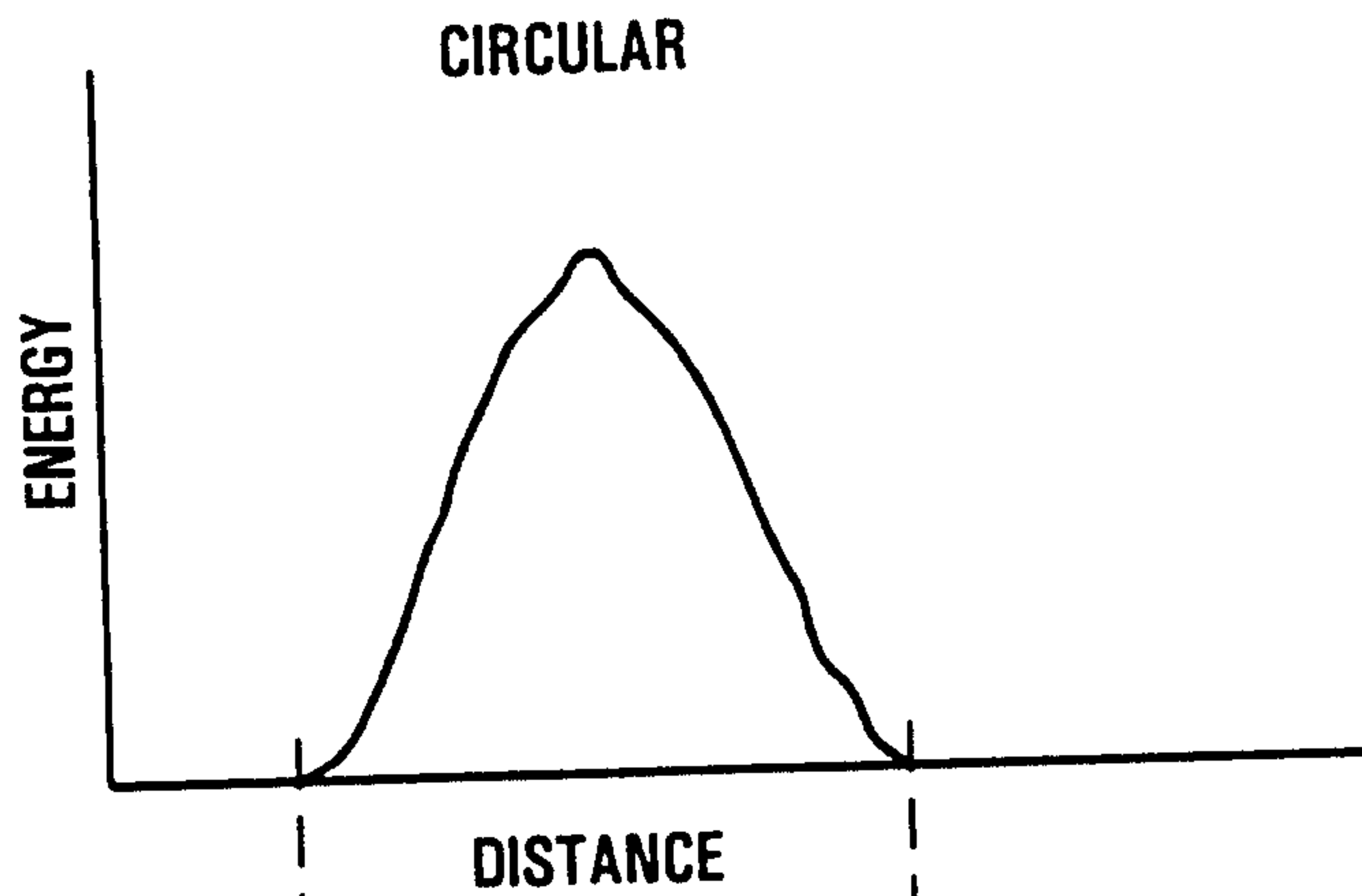


FIG. 1B

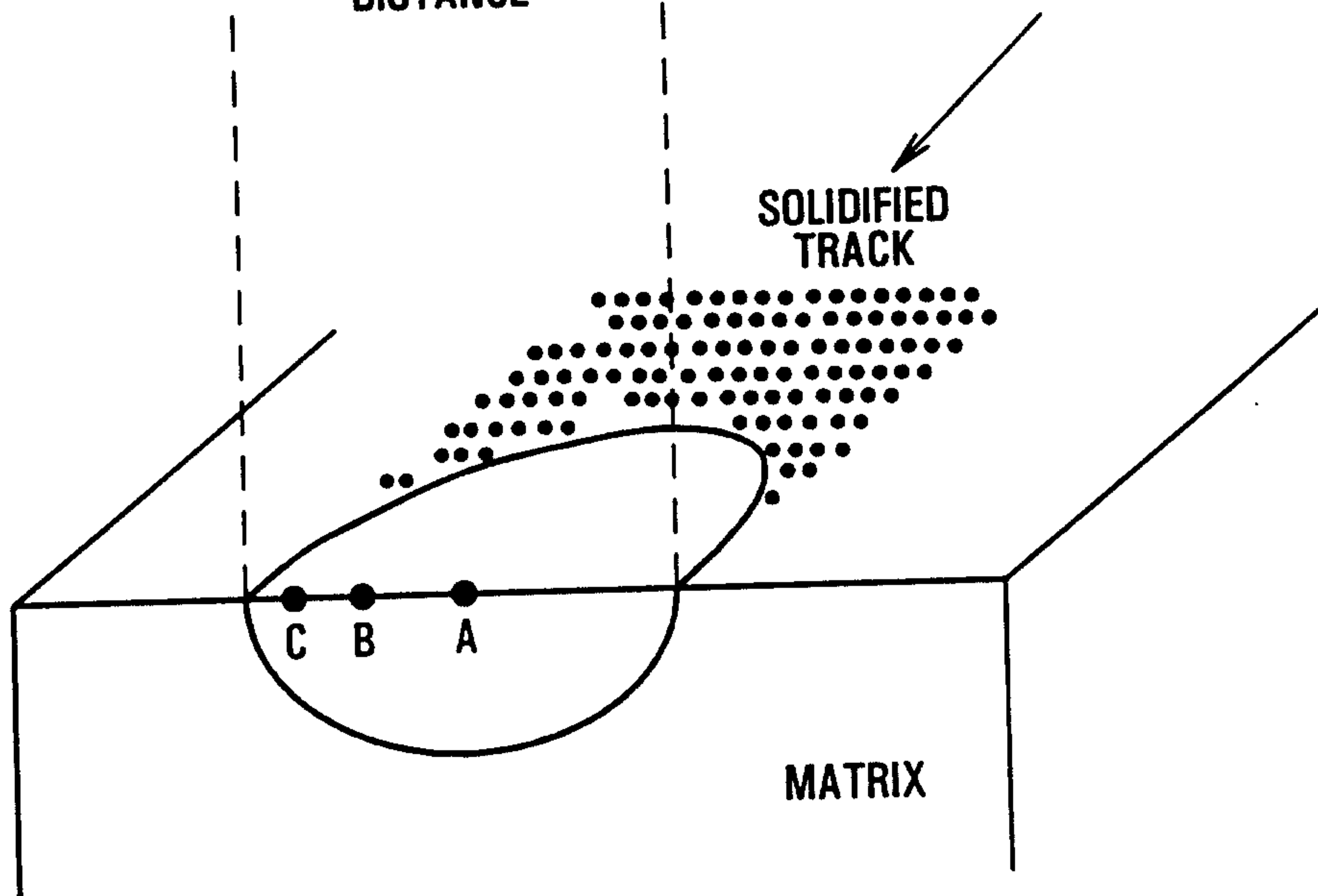
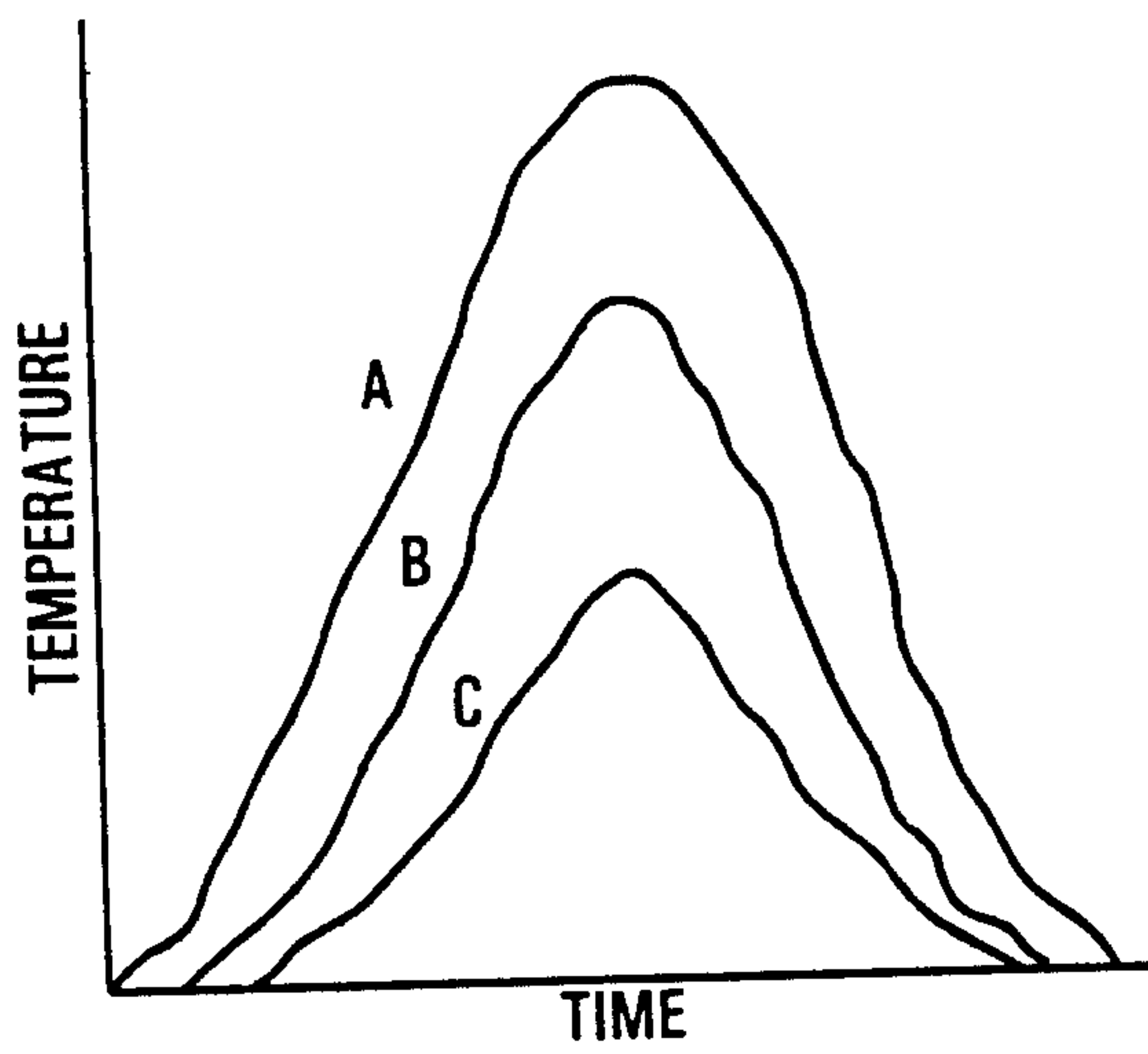
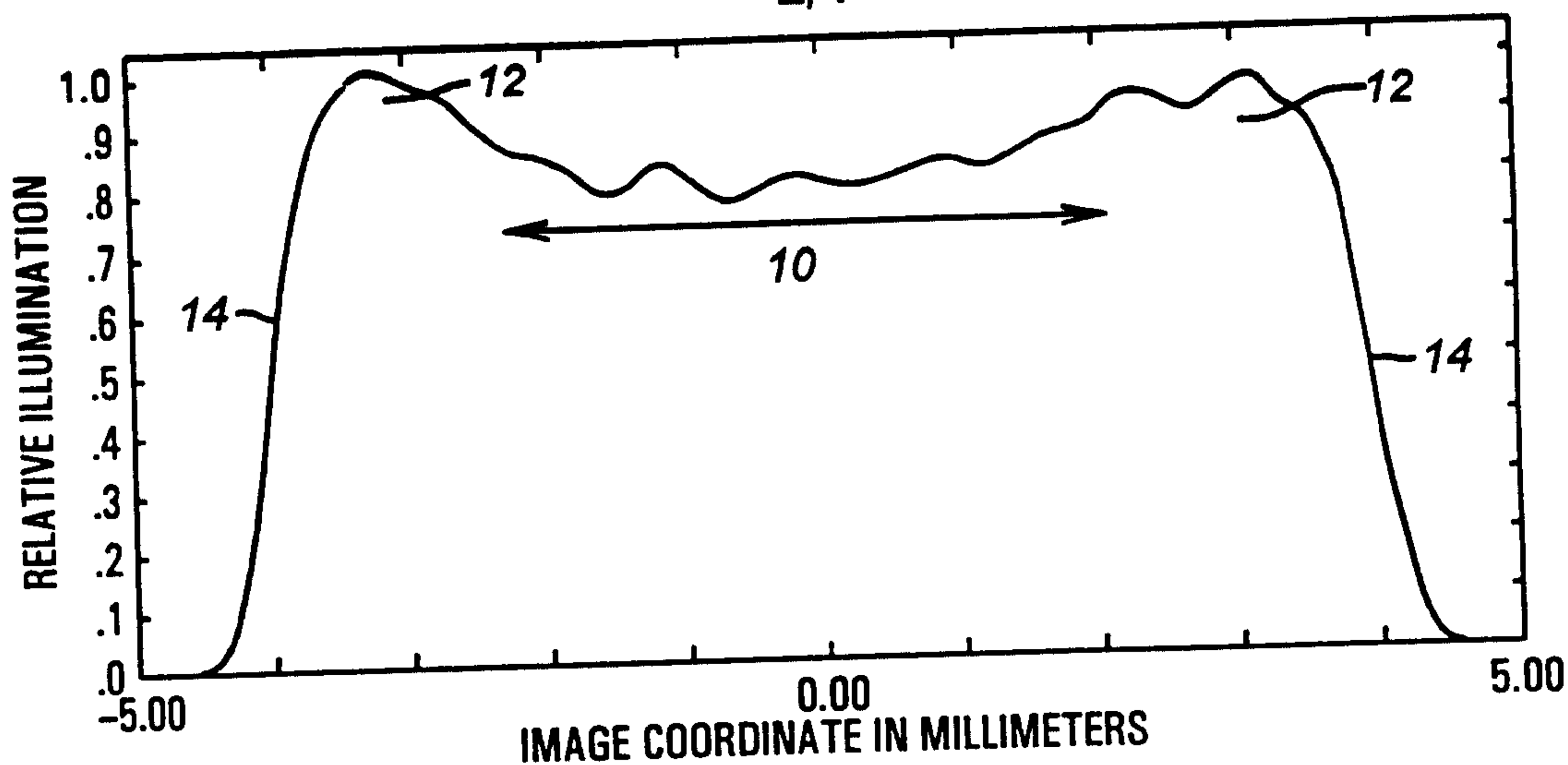


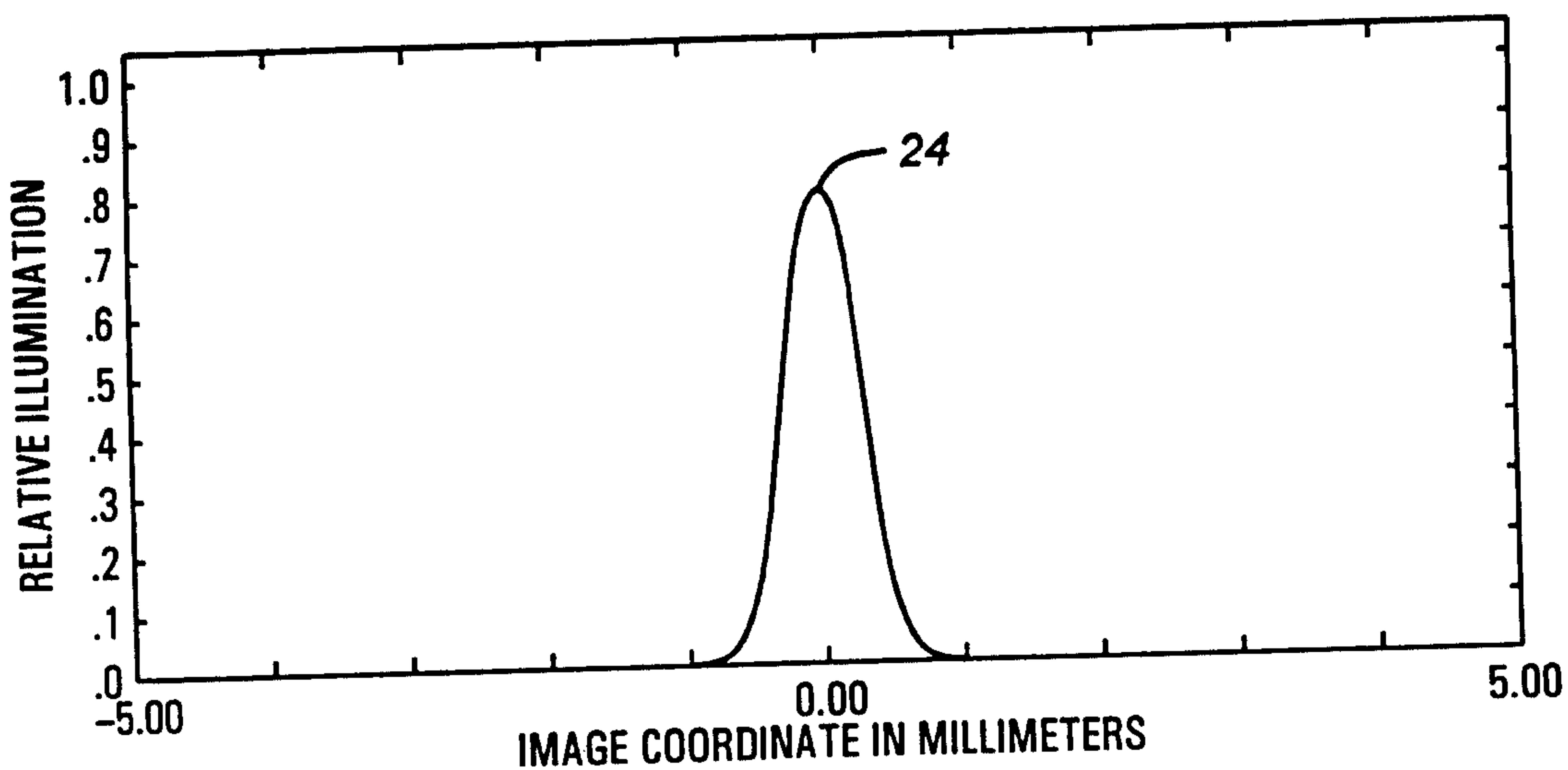
FIG. 1C



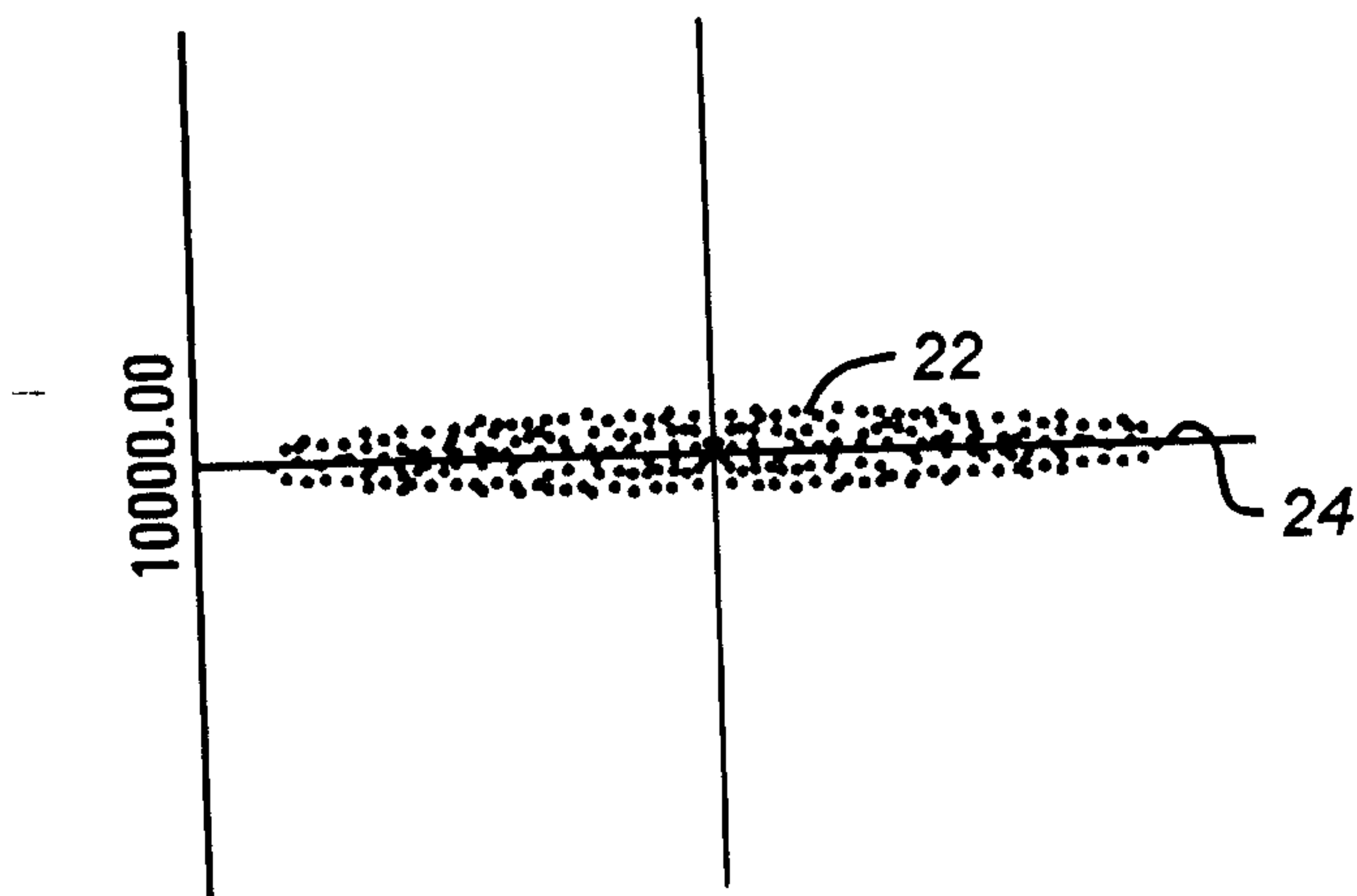
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**FIG. 2A**

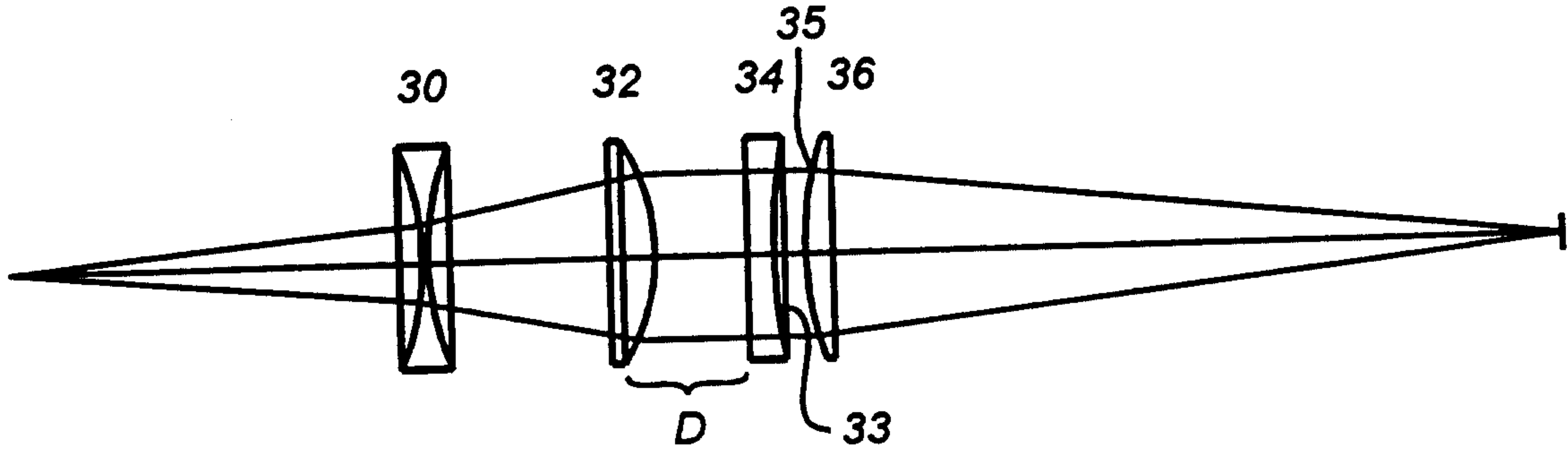


**FIG. 2B**

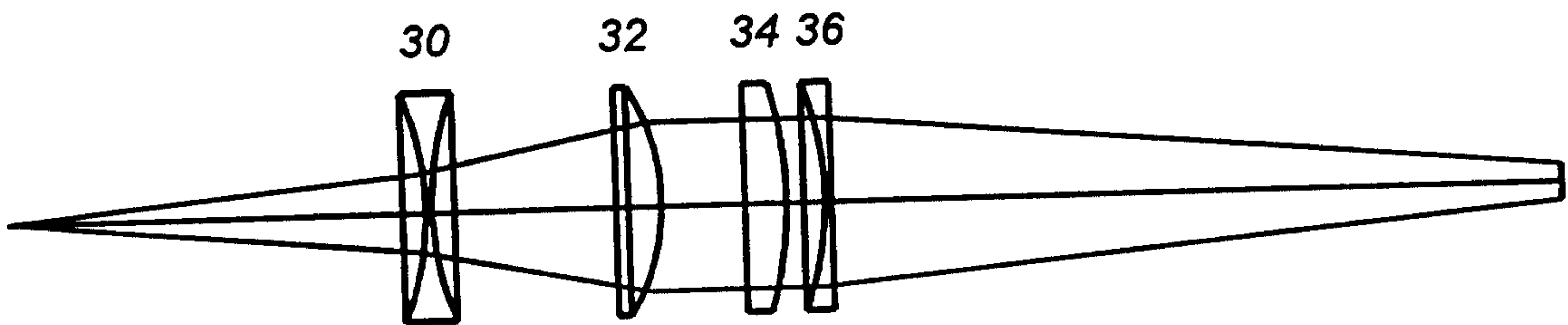


**FIG. 2C**

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**FIG. 3**



**FIG. 4**

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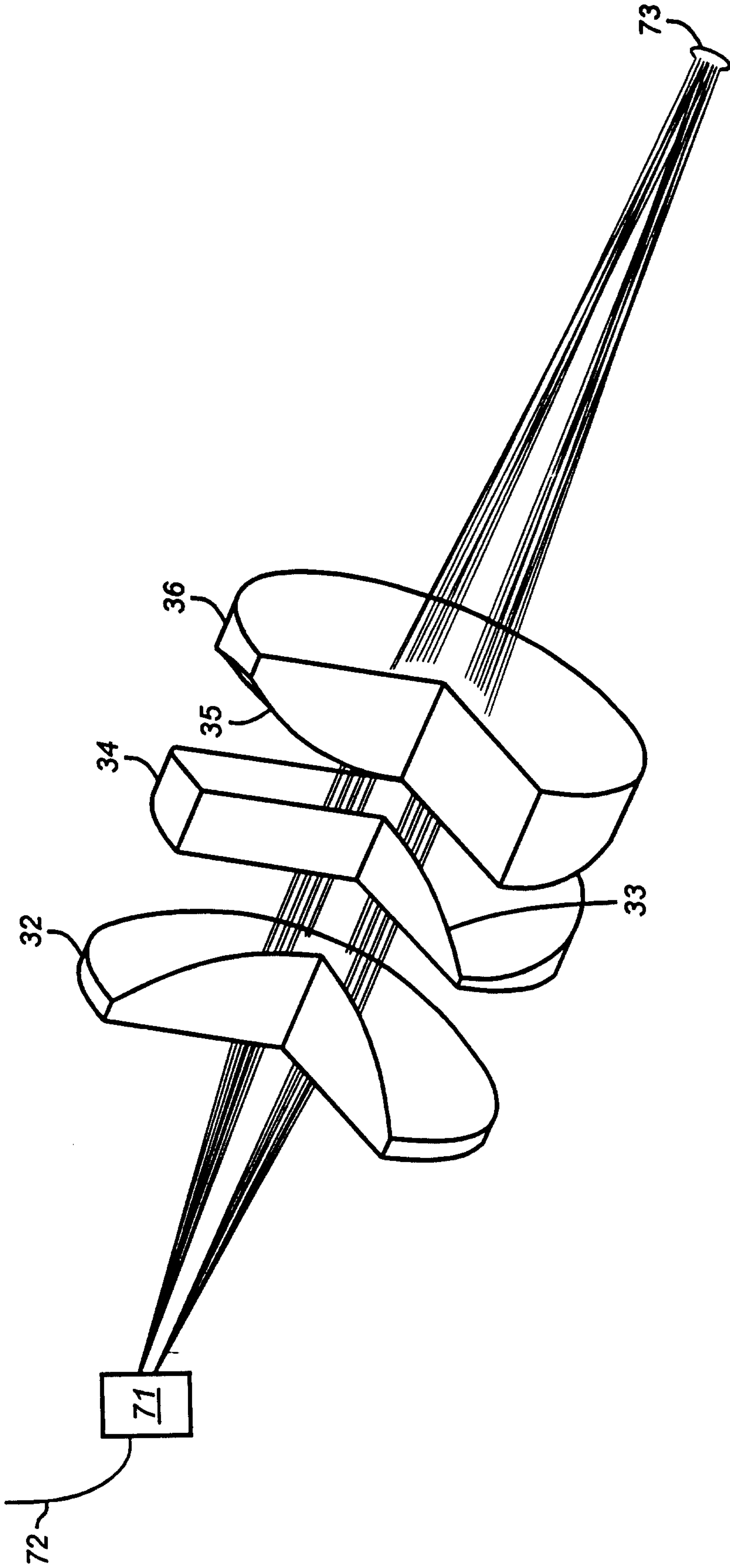


FIG. 5